

**Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**Claims 1-10 (Canceled)**

11. (Previously presented) A process meter, comprising:
  - a sensor which can be mounted in a wall of a vessel for holding or conveying a process medium,
  - an electronics case for meter electronics which is mechanically, particularly rigidly, coupled to said sensor, and
  - at least one vibration absorber, wherein:
    - said electronics case is at least intermittently subjected to vibrations generated in or transmitted via said sensor; and
    - in order to reduce amplitudes of possible vibrations of said electronics case, said at least one vibration absorber which is vibrated at least intermittently in order to dissipate vibrational energy taken into said electronics case is affixed to a wall of said electronics case.
12. (Previously presented) The process meter as set forth in claim 11, wherein:
  - said at least one vibration absorber is positioned at a distance, particularly as far as possible, from a joint between said sensor and said electronics case.
13. (Previously presented) The process meter as set forth in claim 11, wherein:
  - said at least one vibration absorber has a quality factor,  $Q_D$ , which is lower than a quality factor,  $Q_G$ , of said vibrating electronics case.

14. (Previously presented) The process meter as set forth in claim 11, wherein:

    said at least one vibrated vibration absorber has a quality factor,  $Q_D$ , in the range of 1 to 5, particularly on the order of 3.

15. (Previously presented) The process meter as set forth in claim 11, wherein:

    said at least one vibration absorber has a resonant frequency,  $f_D$ , which differs from a resonant frequency,  $f_G$ , of said electronics case by about 10% at the most.

16. (Previously presented) The process meter as set forth in claim 11, wherein:

    said at least one vibration absorber has a resonant frequency,  $f_D$ , which is less than a resonant frequency,  $f_G$ , of said electronics case.

17. (Previously presented) The process meter as set forth in claim 11, wherein:

    said at least one vibration absorber has a mass,  $m_D$ , which is greater than 1% of a mass,  $m_G$ , of said electronics case.

18. (Previously presented) The process meter as set forth in claim 11, wherein:

    said at least one vibration absorber is disposed within said electronics case.

19. (Previously presented) The process meter as set forth in claim 11, wherein:

    said at least one vibration absorber comprises a disk- or cup-shaped plastic body having a, particularly disk- or plate-shaped, metal body fitted or embedded therein.

20. (Previously presented) The process meter as set forth in claim 11, wherein:

    said at least one vibration absorber comprises a plastic body which is affixed to the wall of said electronics case, particularly with adhesive.

21. (New) The process meter as set forth in claim 11, wherein:

    the process meter is selected from a group consisting of: level limit monitors; pressure gauges; electromagnetic flowmeters; vortex flowmeters; Coriolis mass flowmeters; densimeters, viscometers, ultrasonic flowmeters, and ultrasonic level meters.